

SEE and TID Radiation Test Results of Digital Circuits Designed and Manufactured in ST 40nm/45nm/65nm/90nm/130nm CMOS technologies

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Headline



- Circuits tested
 - 5 technologies
 - 8 test vehicles
- Test plan performed over 2009
 - 4 test facilities
 - ~800 test runs

Main SEE HI/proton test results and R&D digressions

- latchup and hard fail results
- SEU cross-sections on 45nm SRAMs
- well tie frequency and SEU
- low-E proton ionization with Low-LET ions

Main TID test results

up to 300 krad_{Si}

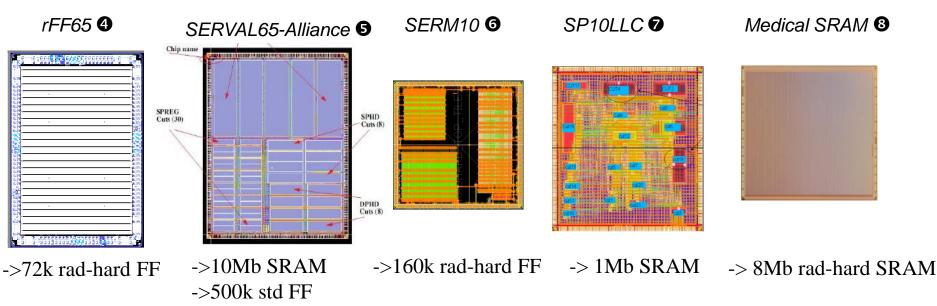
Conclusion

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5 test vehicles tested in 65, 90 and 130nm

- 5 test vehicles in ST CMOS 65nm/90nm/130nm
 - for validation of terrestrial rad-hard Flip-Flops **3**+ **6**
 - for Soft Error Rate characterizations of libraries G
 - for electrical characterization of libraries
 - for validation of terrestrial rad-hard and ULP SRAM ③



pre-characterization with alphas and atmospheric neutrons

set-ups developed by ST and kindly reused for this contract at no cost

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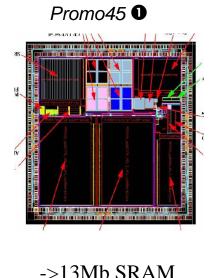


3 test vehicles in 45/40nm

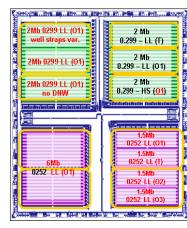


3 test vehicles in ST CMOS 45nm/40nm embedding SRAMs

- libraries validation and <u>PRO</u>cess <u>MO</u>nitoring in the time **0**+ **3**
 - SRAMs, ROMs, standard cells, via chains (back-end stress), ring oscillators (speed meas.), dividers (delay path meas.), IOs, Fuse : 75 M transistors & 24mm²
- for characterization of Single Port SRAM in large memory cuts ②

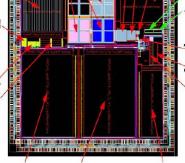


Pantera45 2



->24Mb SRAM





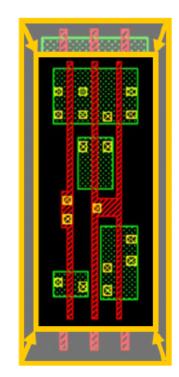
->13Mb SRAM

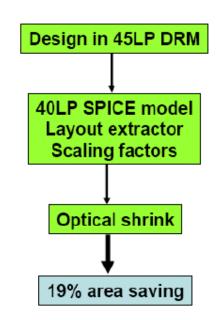
40nm is an optically shrunk technology

What is a shrunk technology?

- Daughter is 10% linear shrink of Mother
- All nominal devices aligned
- Daughter is built-in within mother technology
 - allowing fast transition (same DRM, DRC)

Example of ST Mother (45nm) and Daughter (40nm)





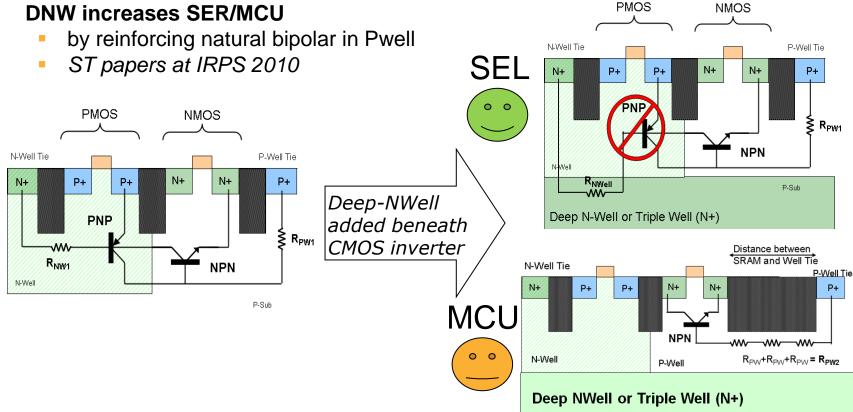
Reminders about ST Deep-NWell (DNW) layer

DNW is reversed-biased N+ buried layer

- Enabling Ultra Low power
- Reducing Noise from substrate

DNW removes SEL

- proven in ST 90/65nm at VDD+40% and 125degC
- ST papers at NSREC'07 and ESA QCA days 2007/2009



Test vehicles overall content



none 0,312Mb

none 0,312Mb

Size

1Mb

2Mb

2Mb

199K

159K

194K

194x2K

2x36K

5Mb

5Mb

2Mb

5Mb

5Mb

2Mb

2Mb

4Mb

2Mb

4Mb

4x40K

8Mb

DNW

both

both

both

both

both

both

both

none

yes

yes

yes

ves

yes

yes

yes

no

no

no

none

none

Test vehicle Techno +50 Mbits of SRAMs Generator Device option name 1 rad-hard terrestrial SRAM covered by SP10LLC SP10LLC 90nm (flash) 1,3µm2 SP10LLC 1,3µm3 SERVAL65 65nm LP DPHD 0.98µm² ~1.5 M of Flip-flops SPHS 0.525µm² SPREG 0.62µm² 6 flavors from production libraries shift-registers plain FF, X4, Rad-hard terrestrial Flip-flop in 2 13T shift-registers plain, X35 shift-registers plain, X4, 9T shift-registers clear, x4, 13T **ROBUSTFF65** 65nm LP largest rFF shift-registers 0.252µ2, 0.299µm², 0.374µm², 0.52µm², PROMO45 45nm LP RPD HS 0.374µm² 0.62µm², 0.98µm², 1.3µm², 4.3µm² **RPD LL** 0.374µm² **RPD HS** 0.299µm² 2 SRAM architectures : PROMO40 40nm LP RPD HS 0.374µm² SP (single port) and DP (dual port) **RPD LL** 0.374um² 0.299µm² **RPD HS** PANTERA45 45nm LP SP SRAM LP1 0.299µm2 2 technologies : 0.299µm2 SP SRAM LP2 standard and Flash compliant SP SRAM LP3 0.299µm2 SP SRAM LP4 0.299µm2 SERM10 90nm (flash) shift-registers largest rFF

Medical

130nm

2 Threshold Voltages :

2 eDRAMs

technologies

8 SRAM areas :

Standard and High VT (low power)

29-03-2011

4.3µm2

stand-alone

Effective test plan



- 4 test campaigns in 2009: RADEF, UCL & PSI (~1 week) and ENEA (50 days)
 - 9-14 ion-LET and 6-8 proton energies
- Extensive Design-of-Experiment:
 - 3 Patterns
 - 10 power supplies
 - 5 Temperatures
 - minimum 2 samples tested per circuit

-474 test conditions -768 test runs

device	Pattern	Power Supply	Temp.	Algorithm	# of runs	
Oct-Dec 2009: ENEA +40days experiments to 296krads						
5 devices	-	Nominal	Room	-	1	
Sept-2009: PSI E	Effective Desig	n of experiment				
Promo45	CKB/ALL0/1	1.0V/1.1V/1.21V	25/125°C	Static	53	
Pantera45	CKB/ALL0/1	1.0V/1.1V/1.21V	25/125°C	Static	50	
rFF65	ALL0/ALL1	1,2V	25/125°C	Static		
SERVAL65	CKB/ALL0/1	1,08V/1.2V/1.32V	25/125°C	Static/Dyn.	60	
SP10LLC	CKB	0,9V/1.2V	25°C/100°C	Dyn./PowerDown	32	
Med. SRAM	CKB/ALL0/1	1.4V/1.5V	25/125°C	Static	59	
RADEF May 2009						
Promo45	CKB	1.0V/1.1V/1.21V	25/125°C	Static/Dyn.	83	
Pantera45	CKB	1.0V/1.1V/1.21V	25/60/80/100/125°C	Static	53	
rFF65	CKB/ALL0/1	0,55V/0,96V/1,08V/1.2V	25/125°C	Static/Dyn.	87	
SP10LLC	CKB	0,9V/1.2V	25°C/100°C	Dyn./P-Down/Stat	53	
UCL March 2009						
Promo40	CKB	1.1V/1.21V	25°C/100°C/125°C	Dynamic	59	
SERM10	CKB/ALL0/1	0.85V/1.2V/1.32V	25/125°C	Static/Dyn.	131	
Med. SRAM	CKB	Nom./BackBias	25/125°C	Static	43	

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Test results for latchup and hard fail



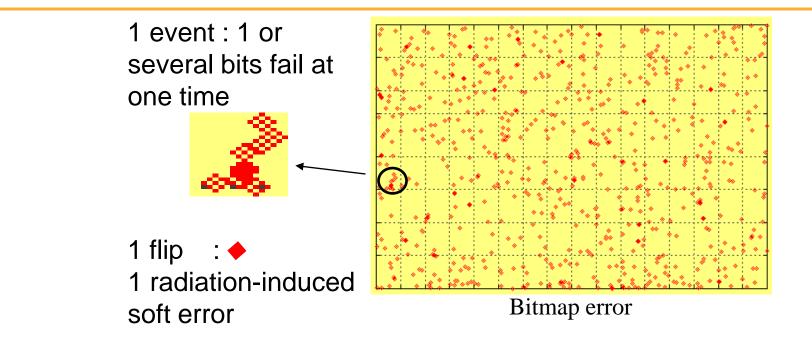
- Rare latchup events at high LET/Vdd/Temp on devices:
 - without Deep N-Well in 90LP / 65LP
- No Latchup ever recorded during irradiations on devices:
 - with Deep N-Well in 65LP / 45LP / 40LP
 - with heavy ions and protons,
 - up to 120 MeV.cm2/mg and VDD + 20% and 125 degC
 - without Deep N-Well in <u>45LP/40LP</u>
 - with heavy ions and protons,
 - up to 120 MeV.cm2/mg and VDD + 10% and 125 degC

• No hard fail or permanent damage ever recorded during all tests

- on circuits in ST CMOS 130nm, 90nm, 65nm, 45nm and 40nm
- with heavy ions up to 120 MeV.cm2/mg
- With proton up to 230 MeV
- VDD up to nominal + 10%
- temperature up to 125degC

Reminders on flips/SBU/MCU/events



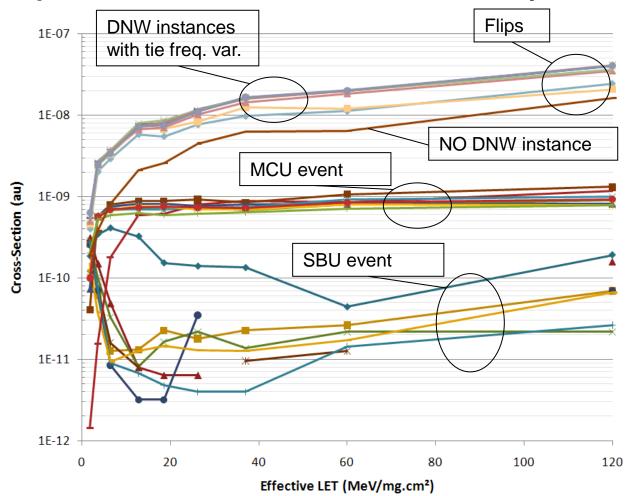


- Single Bit Upset or SBU: 1 event of 1 bit fail
- MCU : multiple upsets
- MBU : MCU in same logic word
- No MBU ever recorded
 - With ad-hoc internal multiplexation (scrambling) in ST memory arrays
- EDAC can be 100% efficient

Focus on HI results on 45nm SRAM test circuit

- Unmitigated asymptotic cross-section 5E-8 to 2E-7 /cm2.bit
- Deep NWell increases SEU cross section by x3

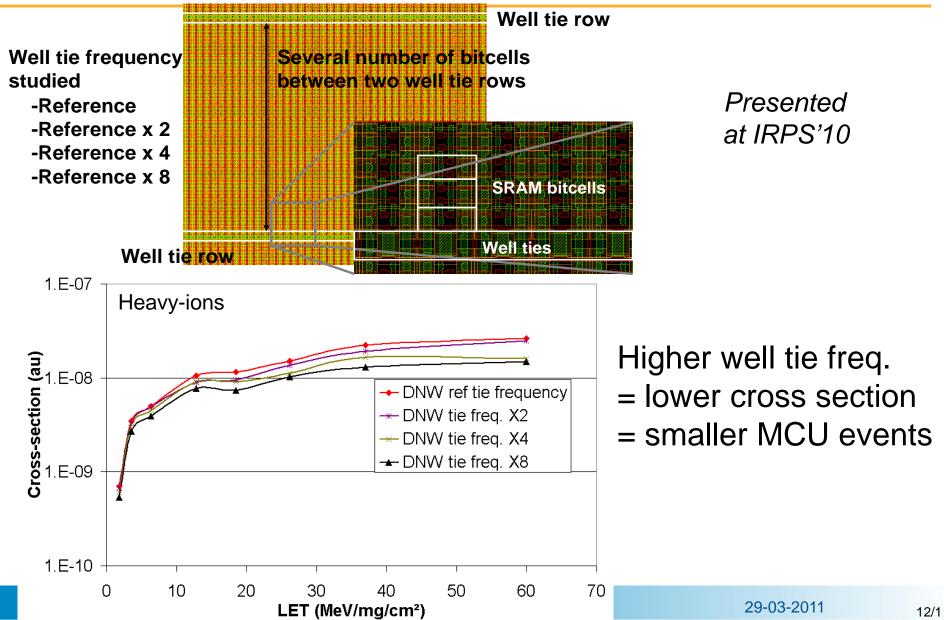
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moDNW CS_SBU •DNW CS_SBU DNW svar8 CS SBU DNW_svar16 CS_SBU DNW_svar32 CS_SBU DNW_svar64 CS_SBU 0252 CS_SBU noDNW CS_MCU DNW CS_MCU DNW_svar8 CS_MCU DNW_svar16 CS_MCU DNW_svar32 CS_MCU DNW_svar64 CS_MCU —0299_01_LLCS_MCU noDNW CS_Flips DNW CS_Flips DNW_svar16 CS_Flips DNW_svar32 CS_Flips DNW_svar64 CS_Flips

Focus on well ties in SRAM array

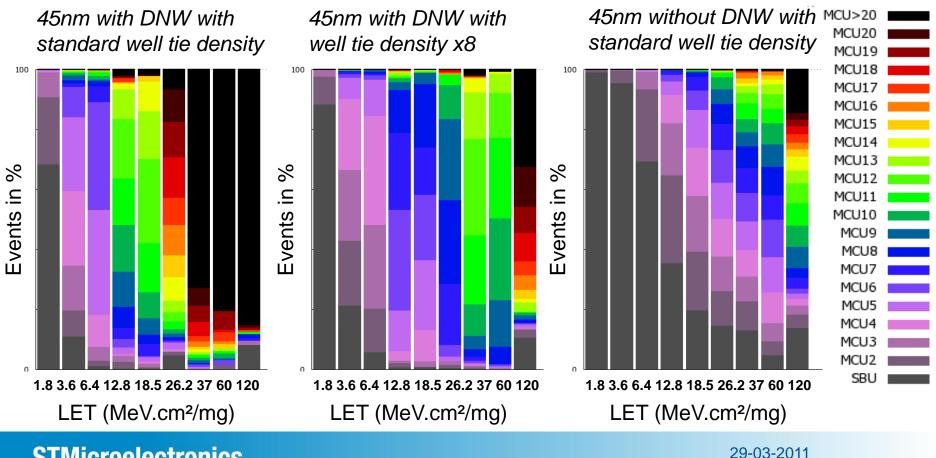




Focus on HI test results 45nm: MCU

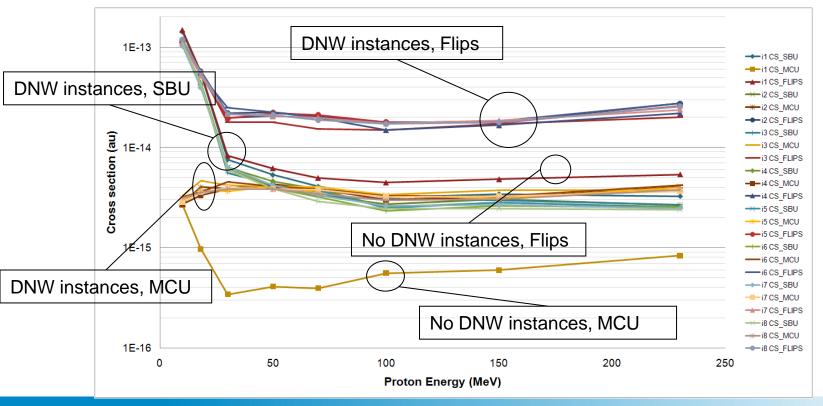


- With DNW Higher tie freq. reduces upsets number per MCU events
 - smaller cross section
 - well tie reduce bipolar amplification
- Smallest number of upset per event is observed for device without DNW



Focus on proton results on 45nm SRAM circuit

- Proton cross-sections 2^E-14 cm2/bit (no DNW) to 9^E-14 cm2/bit (DNW)
- 10 and 20 MeV cross-sections increase attributed to
 - Low-E proton ionization: proton LET @20MeV very small (1/10 LET@1MeV)
 - same behavior on SRAM cell with higher Qcrit (90nm).
 - 100MeV residue pollution: probable since MCU cross-sections increase as well
- Specific 1MeV 3MeV proton measurement needed to conclude



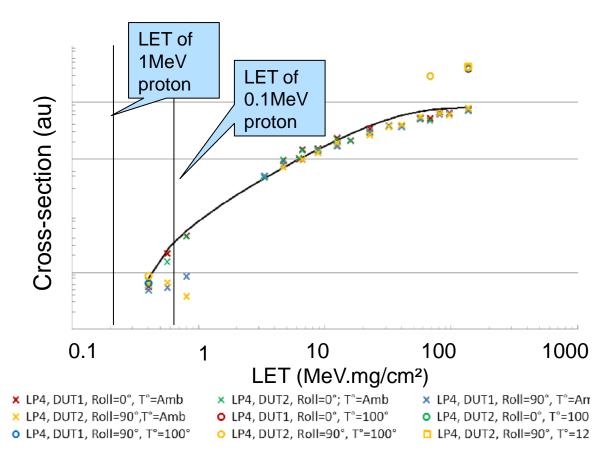
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R&D digression: using low-LET ions to emulate Proton ionization

- Facility:
 - UCL, Be

Experimental details:

- Helium ion
- 0.3-0.5-0.7 MeV.cm²/mg
- Temp. & roll angle
- Test vehicle:
 - 40nm SRAMs
- No cross section increase
 @ Low LET



TID test results at ENEA with Cobalt 60 source

300krad_{si} TID Experimental details at ENEA, Rome

- all devices power supplied at nom. VDD
- all devices with input signals tied to specified values (not floating)
- preferential pattern
- dose rate ~292radSi/h
- 24hours annealing biased @ Room temp. + 100h annealing biased @100°C
- current monitored on all power lines of each board. Sampling 30minutes
 - +2000 read points per device

Four technologies (5 test vehicles) tested

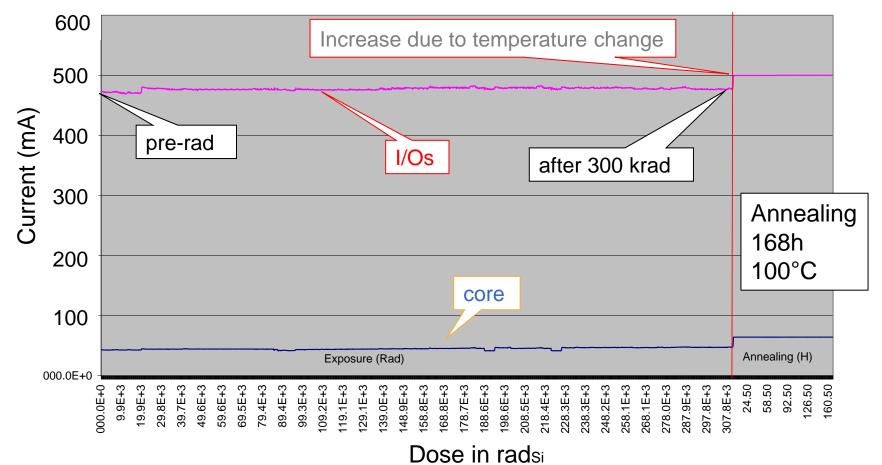
- 45nm: Promo45 SRAM
- 65nm: rFF65 no DNW & SERVAL65
- 90nm: SP10LLC
- 130nm Medical SRAM
- No over consumption at 300kradSi
 - zero current increase on all power domains
- 100% functionality at 300kradSi
 - first order functional parameters unchanged

Evidence of TID immunity @ 300kradSi

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Focus of TID results in 45nm

- 100% functionality and no overconsumption after
 - +1000h of continuous gamma irradiation @252radSi/h
 - 100h annealing @100°C



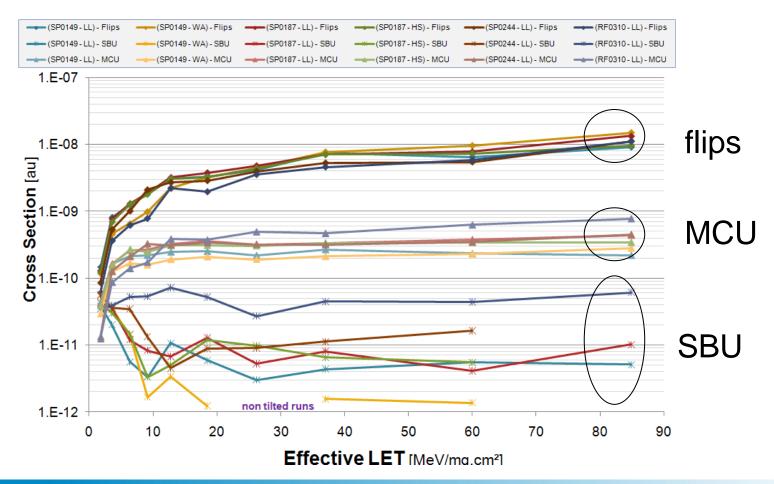
Radiation hardness further improves... in 45/40n

- SEL immunity verified under heavy ions & protons
 - Up to 120MeV.cm²/mg & 125°C & Vdd + 10%
 - Up to 230MeV & 125°C & Vdd + 10%
- Low SEE cross-section & Low MCU/MBU rate
 - Reduced bipolar effect inside wells (article list)
- No TID effect up to 300krad_{si}

Technology	Deep NWell	SEU rate in GEO @ solar quiet	SEL immunity
CMOS065LP	yes	1.4e-6 upset/bit/day	yes
CMOS045LP	yes	1.6e-7 upset/bit/day	yes
CMOS045LP	no	3e-8 upset/bit/day	yes

Radiation hardness further improves ... in 32nm

- SRAM SEL immunity verified under heavy ions (beyond the scope of this contract)
 - Up to 85MeV.mg/cm² & 100°C & Vddnom + 10%
- Sat. cross section with DNW < 6^e-8cm²/bit



Conclusions



- 8 circuits jointly tested ESA and ST-Crolles from March to Dec. 2009
 - with heavy ions, protons and gamma rays
 - using ESA certified beams and test methods
 - ~800 test runs: VDD, temp, pattern, clock, facility, algorithm...
- High intrinsic radiation hardness measured with heavy ions and protons
 - no latchup nor hard fail
 - up to 120 MeV.cm²/mg
 - low SEU cross sections with heavy ions / protons
 - EDAC 100% efficient with appropriate scrambling
 - Low energy protons not clearly observable at PSI
- Very high intrinsic radiation robustness measured with gamma rays
 - no over-consumption and 100% chip functionality at 300krad for every DUTs
 - no longer need for costly TID mitigation techniques (guard rings, edgeless transistors, ...)